

**Silicon Valley  
Patent Group LLP**

2350 Mission College Blvd  
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Santa Clara, CA 95054

## Facsimile Cover Sheet

Date:	August 3, 2004
To:	Veronica Augburn Fax: 571-273-0988
From:	David E. Steuber Tel: 408/982-8200 extension 1 Fax: 408/982-8210
Re:	Application No. 10/003,908
No. of pages	5 (including this cover sheet)

Ms. Augburn:

At the request of Examiner Anita Alanko, please find enclosed copies of the following documents in connection with the above-referenced patent application:

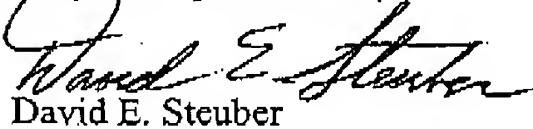
- Facsimile Cover Sheet dated November 12, 2003
- Revocation Of Power Of Attorney With New Power Of Attorney And Change Of Correspondence Address dated November 3, 2004
- Statement Under 37 CFR 3.73(b) dated November 3, 2004

Also enclosed is a copy of an Auto-Reply Facsimile Transmission verifying that the above documents were received by the U.S. Patent and Trademark Office on November 12, 2003.

I would appreciate it if you would make sure that the above documents are entered into the file for the above-referenced application.

If you have any questions, please call me at the above number.

Respectfully submitted,

  
David E. Steuber

## Auto-Reply Facsimile Transmission



TO: Fax Sender at 408 982 8210

Fax Information

Date Received:

11/12/2003 7:30:31 PM [Eastern Standard Time]

Total Pages:

3 (including cover page)

**ADVISORY:** This is an automatically generated return receipt confirmation of the facsimile transmission received by the Office. Please check to make sure that the number of pages listed as received in Total Pages above matches what was intended to be sent. Applicants are advised to retain this receipt in the unlikely event that proof of this facsimile transmission is necessary. Applicants are also advised to use the certificate of facsimile transmission procedures set forth in 37 CFR 1.8(a) and (b), 37 CFR 1.6(f). Trademark Applicants, also see the Trademark Manual of Examining Procedure (TMEP) section 306 et seq.

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11/12/2003 17:30 FAX 408 982 8210		SILICON VALLEY PATENT GR 1/001	
<b>Silicon Valley Patent Group LLP</b>		2350 Mission College Blvd. Suite 360 Sunnyvale, CA 95084	Tel: 408/982-8200 Fax: 408/982-8210
<b>Facsimile Cover Sheet</b>			
Date:	November 12, 2003	First Inventor:	William R. Entley
To:	US Patent & Trademark Office Fax: 703-872-9310 Tel: 703-872-9300	Title:	In Situ Plasma Process To Remove Fluorine Residues From The Interior Surfaces Of A CVD Reactor
From:	David E. Stauber Tel: 408/982-8200 ext. 1 Fax: 408/982-8210	Serial No.:	10/003,008
Pages:	2 (excluding cover sheet)	Examiner:	Anita Karen Alanko

Enclosed for filing in the above-identified application are the following:  
Revocation and Power of Attorney with New Power of Attorney and  
Change of Correspondence Address (1 page)  
Statement Under 37 CFR 3.73(b) (1 page)

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PAGE 10 \* RCVD AT 11/12/2003 7:30:31 PM [Eastern Standard Time] \* SVR:USPTO-EFXRF-10 \* DNIS:2730988 \* CSID:408 982 8210 \* DURATION (mm:ss):01:26

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**Facsimile Cover Sheet**

Date:	November 12, 2003
To:	US Patent & Trademark Office Fax: 703-872-9310 Tel: 703-872-9309
From:	David E. Stuber Tel: 408/982-8200 ext. 1 Fax: 408/982-8210
Pages	2 (excluding cover sheet)

First Inventor:	William R. Entley
Title:	In Situ Plasma Process To Remove Fluorine Residues From The Interior Surfaces Of A CVD Reactor
Serial No.:	10/003,908
Examiner:	Anita Karen Alanko

Enclosed for filing in the above-identified application are the following:

**Revocation and Power of Attorney with New Power of Attorney and  
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 Statement Under 37 CFR 3.73(b) (1 page)**

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